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Docket No.: MUH-12818

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By: 

Date: June 28, 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applic. No. : 10/675,049 Confirmation No.: 5871
Applicant : Ioannis Dotsikas
Filed : September 30, 2003
Title : Method and Furnace for the Vapor Phase Deposition of
Components onto Semiconductor Substrates with a Variable
Main Flow Direction of the Process Gas
Art Unit : 2818
Examiner : Duang A. Le
Docket No. : MUH-12818
Customer No. : 24131

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR 1.97(c)(1)

Hon. Commissioner for Patents
Alexandria, VA 22313-1450

Sir:

In accordance with 37 CFR 1.98 copies of the following patents and/or publications are cited herewith:

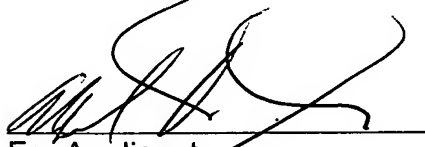
Patent Abstract of Japan JP 04-343412 (Harashima Keiichi), dated November 30, 1992;

Patent Abstract of Japan JP 02-074587 (Watabe Junichi, et al.), dated March 14, 1990;

Japanese Office Action dated May 15, 2006.

In accordance with 37 CFR 1.97(e) the undersigned herewith states that each item of information contained in the information disclosure statement was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

Respectfully submitted,


For Applicant

Alfred K. Dassler
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Date: June 28, 2006

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FORM PTO-1449 (SUBSTITUTE) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (37 CFR 1.98(b))				Attorney Docket No.: MUH-12818 Applicant Ioannis Dotsikas Filing Date September 30, 2003 Group Art Unit 2818			
U.S. PATENT DOCUMENTS							
EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
	A						
	B						
	C						
	D						
	E						
	F						
	G						
	H						
	I						
FOREIGN PATENT DOCUMENT							
		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES NO
	J	04-343412	11/1992	Japan			
	K	02-074587	03/1990	Japan			
	L						
	M						
	N						
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
	O						
	P						
EXAMINER				DATE CONSIDERED			
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							